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## U.S. UTILITY Patent Application

APPL NUM 10009910	FILING DATE 12/12/2001	CLASS 438	SUBCLASS	GAU 2812	EXAMINER S079
**APPLICANTS: Iida Makoto; Kimura Masanori;					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP01/03101 04/10/2001					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-113297 04/14/2000					
PG-PUB	<input type="checkbox"/> DO NOT PUBLISH	RESCIND			
Foreign priority claimed 35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO 81839.0107		
Verified and Acknowledged Examiner's initials					
TITLE : Silicon wafer, silicon epitaxial wafer, anneal wafer and method for producing them U.S. DEPT. OF COMM./PAT. & TM-PTO-436L(Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drawg.	Fig.s Drawg.	Print Fig.
TERMINAL		Primary Examiner		
DISCLAIMER		Application Examiner		
PREPARED FOR ISSUE				
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